

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**In re Application of:**

Nathan R. Brown

**Serial No.:** 10/715,267

**Filed:** November 17, 2003

**For:** METHODS FOR POLISHING  
SEMICONDUCTOR DEVICE  
STRUCTURES BY DIFFERENTIALLY  
APPLYING PRESSURE TO SUBSTRATES  
THAT CARRY THE SEMICONDUCTOR  
DEVICE STRUCTURES

**Confirmation No.:** 4590

**Examiner:** S. Macarthur

**Group Art Unit:** 1792

**Attorney Docket No.:** 2269-4375.1US  
(1999-1029.01/US)

VIA ELECTRONIC FILING  
January 26, 2009

**RESPONSE TO RESTRICTION REQUIREMENT**

Mail Stop Amendment  
Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

Examiner:

This Response follows the Restriction Requirement of December 26, 2008, the shortened statutory period for response to which expires on January 26, 2009.

A listing of claims begins on page 2 of this paper; and

Remarks start at page 7 of this paper.